Freiberg
Instruments

RESmap

High precision resistivity mapping

Automated SiC Process Control

Deviations in resistivity within SiC crystals are of significant interest for material processing and quality control. The eddy-current based RESmap device offers high sensitivity and repeatability through integrated temperature compensation and self-calibration routines.

Learn more

Si, SiC, GaN, GaAs, InP and more

Materials

Automated X-Y mapping stage

Single and multi-point measurement, resolution: 1 ± 0.1 mm

Resistivity range

1 – 100 mOhm cm

>20

Wafers/hour throughput

Sigma

< 0.15 %

Exceptional repeatability

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RESmap

w x h x d
465 X 550 X 600 mm

Wafers, boules + ingots slabs

Processing geometries

Compliant with

SEMI MF 673

3

Models: Handheld, automation ready and fully automatic with robotic arms

Integrated distance and temp sensors

± 5 % accuracy

Effortless calibration

Reducing setup time and ensuring long-term reliability